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Proceedings of Symposium on Design, Test, Integration & Packaging of MEMS/MOEMS (DTIP 2014)

Bernard Courtois, Jean-Michel Karam, Romolo Marcelli, Souhil Megherbi,
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► **To cite this version:**

Bernard Courtois, Jean-Michel Karam, Romolo Marcelli, Souhil Megherbi, Yoshio Mita, et al. (Dir.).
Proceedings of Symposium on Design, Test, Integration & Packaging of MEMS/MOEMS (DTIP 2014).
Vice General Chair: Pascal NOUET. EDA Publishing, 2014. lirmm-01434883

HAL Id: lirmm-01434883

<https://hal-lirmm.ccsd.cnrs.fr/lirmm-01434883>

Submitted on 21 Jul 2020

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2014 Symposium on Design, Test, Integration and Packaging of MEMS/MOEMS

(DTIP 2014)

**Cannes, France
1-4 April 2014**



**IEEE Catalog Number: CFP14DTI-POD
ISBN: 978-1-4799-3221-4**



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